PATENT ABSTRACTS OF JAPAN

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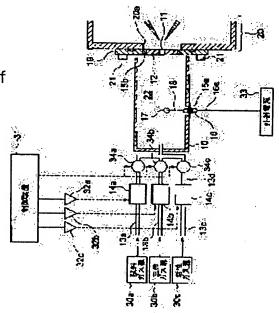
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(54) IONIZATION APPARATUS FOR MASS SPECTROMETRY AND IONIZATION METHOD (57) Abstract:

PROBLEM TO BE SOLVED: To provide an ionization apparatus for mass spectrometry and an ionization method with which a damage of a function of an ion discharge body caused by deposition and accumulation of a carbon and a polymer organic matter is repaired in a short period of time, and the damage of the function is prevented.

SOLUTION: The ion discharge body 17 is set in an cylindrical container 10. One end of the container 10 is connected to a mass spectrometry part 20 through an aperture 12 having an opening 11, and the other end is connected to pipes 13 arranged for introducing gases. The pipes arranged for introducing gases, 13a, 13b and 13c are equipped with a first open/close valve 14a, a second open/close valve 14b and a third open/close valve 14c, and a first mass flow controller 34a, a second



mass flow controller 34b and a third mass flow controller 34c respectively, and constitutes an integrated system of the gas introducing pipes 13. Further, opening and closing actions of the valves 14a, 14b and 14c are electrically or pneumatically controlled each independently.

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